Abstract

A system for testing semiconductor components contained on a substrate, such as a wafer, a panel, a leadframe or a module, includes an interconnect configured to electrically engage all of the components on the substrate at the same The interconnect includes a switching configured to selectively apply test signals to selected components, to electrically isolate defective components and to transmit test signals from selected groups of components. The system also includes a test apparatus, such as a wafer prober or a carrier for handling the substrate. A method for testing includes the steps of providing the interconnect having the switching network, and controlling test signals to the components using the switching network to perform various test procedures, such as functionality tests, parametric tests and burn-in tests.

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